

ALTEC Equipment



New Modular EpiCentre Deposition Stage for MBE applications

The EC-I range of EpiCentre deposition stages consists of an 'in-line' design presenting the substrate parallel to the mounting flange. The EC-I series provides substrate heating with a number of proven modular options offering substrate rotation, electrical biasing and axial translations to set the substrate height and to facilitate substrate transfer.

The EC-I series is the latest model in the very successful range of EpiCentre stages, providing state-of-the-art performance for various growth and deposition techniques including MBE, sputtering and CVD. It represents the latest advance in modular 'in-line' deposition instruments which offer continuous substrate heating, rotation, biasing, and facilities for substrate transfer, while maintaining true UHV compatibility.

The series includes models to accommodate SEMI standard wafers from 2" to 200mm diameter, and special substrate cradles can be provided to accommodate specific substrate shapes and designs up to 200mm (8.5") diameter.

The stages can be mounted in any orientation, although they are most commonly mounted vertically with the wafer facing up or down and parallel to the mounting flange. Other orientations can be accommodated with special wafer holders. Options are also available to configure EpiCentres for higher pressure and corrosive environments.

The series has a full suite of options including choice of system mounting flanges, manual or pneumatic substrate shutters and thermocouple materials.

For more information or to request the new EpiCentre range brochure please visit www.uhvdesign.com.



EC-I In-line Deposition Stage